

Atomic Distribution of Al and Phase Transformation in β -(Al_xGa_{1-x})₂O₃

Hsien-Lien Huang, Jared Johnson and Jinwoo Hwang

The Ohio State University, Columbus, Ohio, United States

β -Ga₂O₃ has gained tremendous attention as a promising transparent conductive oxide, ultra-wide band material due to its unique advantages including a large band gap energy (~ 4.8eV), high breakdown voltage, and its availability as high quality bulk grown single crystals [1]. However, realizing its full potential as a semiconductor material requires the manipulation and control of its band gap, which could enable novel heterostructure designs for carrier confinement and field effect transistors or deep UV optoelectronic devices. Recent efforts have indicated that the bandgap of β -Ga₂O₃ can be engineered through the incorporation of Al [2], forming β -(Al_xGa_{1-x})₂O₃ with a band gap up to 8.8 eV. High crystalline quality β -(Al_xGa_{1-x})₂O₃ structures with Al composition up to x=40% have been achieved using metalorganic chemical vapor deposition (MOCVD) [1] and a high mobility two-dimensional electron gas has been demonstrated to form at a β -(Al_xGa_{1-x})₂O₃/Ga₂O₃ interface [2]. Ultimately, advancing these alloyed β -Ga₂O₃ epitaxial films requires the precise control of the point defects that critically influence their important properties. And their exact control requires attaining the essential detailed atomic scale structural information, which will provide key information on their formation during growth and their impact on properties.

Here, we present the atomic scale characterization of β -(Al_xGa_{1-x})₂O₃ and the observation of phase transformation in (Al_xGa_{1-x})₂O₃ thin films. Employing the unprecedented resolution and chemical sensitivity generated by quantitative scanning transmission electron microscopy (STEM) [3], we specified the exact substitutional positions of the alloying-element Al in molecular beam epitaxy (MBE) and MOCVD grown β -(Al_xGa_{1-x})₂O₃ films (Fig. 1). Quantitative Al site occupancy results were then correlated with density function theory (DFT) and strain information acquired through electron nanodiffraction to better understand the critical thicknesses of β -(Al_xGa_{1-x})₂O₃ films for superlattice structure synthesis. Additionally, quantitative STEM was performed to detail planar defect structures that develop with increasing Al content within β -(Al_xGa_{1-x})₂O₃ films (Fig. 1(e) and (f)). These defect structures revealed a configuration similar to the recently discovered divacancy – interstitial complexes found in β -Ga₂O₃ bulk crystals [4]. To provide an accurate identification of the defect structures, the exact position and composition of each atomic column was determined and then utilized by DFT to reveal their electronic behavior. Furthermore, the mixture of β and γ phases in (Al_xGa_{1-x})₂O₃ thin films were investigated using STEM imaging and nanodiffraction (Fig. 2). Driven by the strain induced from the configurational relaxation during Al incorporation, the rotations of the β phase and introduction of the defective spinel structure were identified. In this STEM investigation, we obtained critical atomic scale defect information that provides guidance to the growth of β -(Al_xGa_{1-x})₂O₃ with controlled properties. We acknowledge support by the Department of Defense, Air Force Office of Scientific Research GAME MURI Program (Grant No. FA9550-18-1-0479).

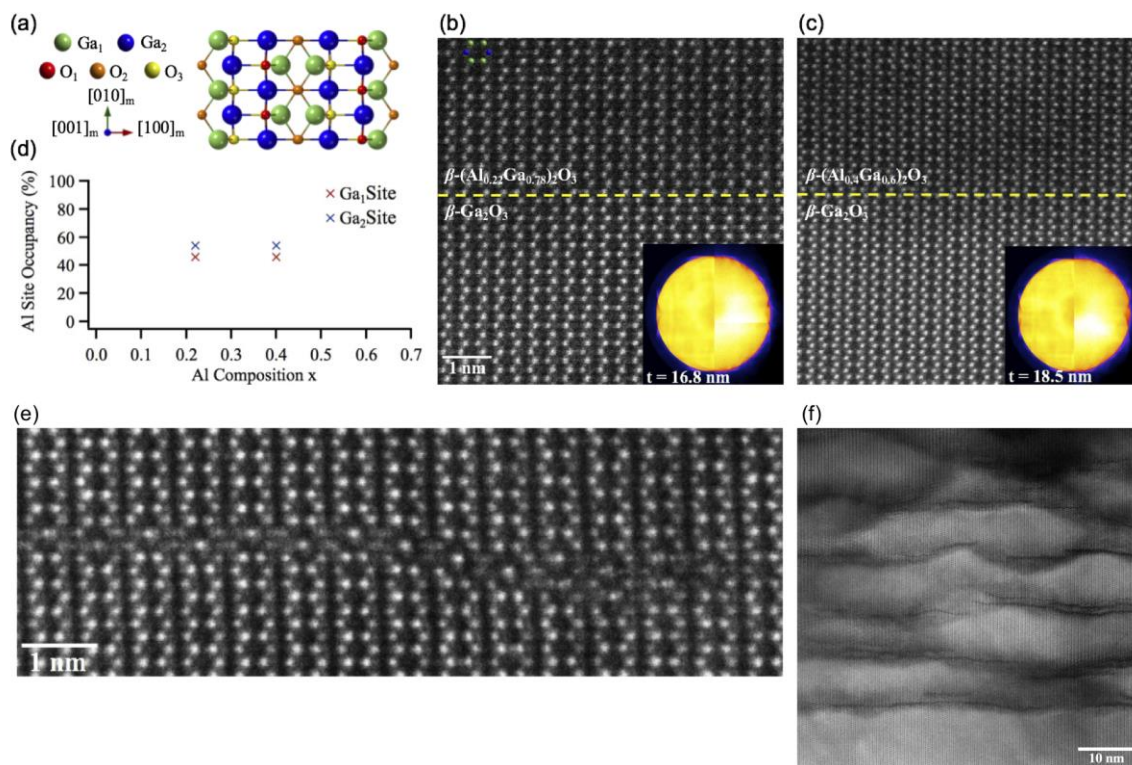


Figure 1. (a) Crystal structure of β -Ga₂O₃ along the [001]_m direction. (b) and (c) HAADF STEM images of (b) β -(Al_{0.22}Ga_{0.78})₂O₃ and (c) β -(Al_{0.40}Ga_{0.60})₂O₃ films used for the quantitative analysis of Al site occupancy. Inset are the experimental PACBED patterns acquired from the β -Ga₂O₃ substrate and the corresponding multislice simulated patterns, indicating a 16.8 nm and 18.5 nm thick TEM sample for the β -(Al_{0.22}Ga_{0.78})₂O₃ and β -(Al_{0.40}Ga_{0.60})₂O₃ films, respectively. (d) Quantitative STEM data showing the Al site occupancy (%) in the Ga₁ (red x) and Ga₂ (blue x) sites versus the Al composition of the film. The HAADF STEM images reveal planar defects in (e) a β -(Al_{0.40}Ga_{0.60})₂O₃ epitaxial film and (f) a β -(Al_{0.56}Ga_{0.44})₂O₃ superlattice structure.

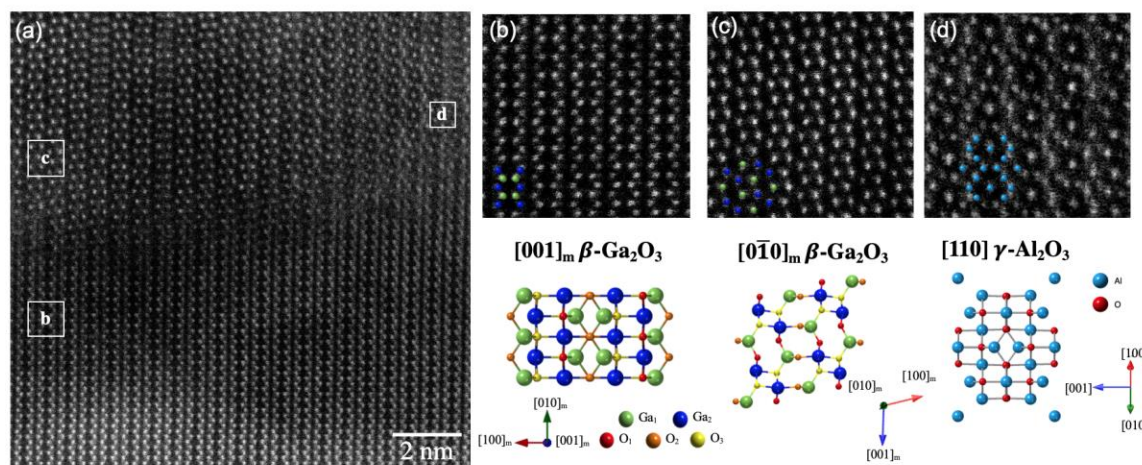


Figure 2. Atomic resolution HAADF STEM images of the (Al_{0.40}Ga_{0.60})₂O₃ film grown on β -Ga₂O₃ substrate. (a) The first 12 nm of the (Al_{0.40}Ga_{0.60})₂O₃ film demonstrating three distinct growth structures. (b) (010) β -(Al_{0.40}Ga_{0.60})₂O₃ growth with the model orientated along the [001]_m imaging direction. (c) (001) β -(Al_{0.40}Ga_{0.60})₂O₃ growth displaying a 90° rotation of the (010) β -Ga₂O₃. (d) [110] γ -Al₂O₃ growth.

(Al_{0.40}Ga_{0.60})₂O₃ and a model oriented along the corresponding [010]_m imaging direction. (d) (110) γ -(Al_{0.36}Ga_{0.64})₂O₃ phase transformation region with a model of [110] γ -Al₂O₃.

References

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